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(54) Microstructure and method of forming the same

(57) There is provided a microstructure comprising a substrate 10, support members 13, 13', a lever 12 and an electrode 17 formed on the lever is characterized in that said support members support said substrate and said beam and/or the electrode section with a void in-

terposed therebetween and an electrode is formed on the lower surface of said beam. There are also provided a method of forming such a microstructure and an electrostatic actuator having a beam that is displaced by applying a voltage to the electrodes of the actuator.

FIG. 3



